

Form PTO-1449				ATTY. DOCKET NO. 4249-0112P		APPLICATION NO. 10/680,229		
INFORMATION DISCLOSURE CITATION IN AN APPLICATION (Use several sheets if necessary)				APPLICANT Kui YAO et al.		FILING DATE October 8, 2003		
				GROUP Unassigned				
U.S. PATENT DOCUMENTS								
EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE	
/BT/	US 6,355,185	B1	2002-03-12	Kubota				
/BT/	US 2003/0134156	A1	2003-07-17	Kim et al.				
FOREIGN PATENT DOCUMENTS								
	Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION YES NO
/BT/	UK	2161647	A	1986-01-15	UNITED KINGDOM			
	JP	03-283583		1991-12-13	JAPAN			ABS
	SG	9703488-8		1997-11-07	SINGAPORE			
/BT/	JP	2000-315827		2000-11-14	JAPAN			ABS
OTHER DOCUMENTS (Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.)								
/BT/	Morten et al., Resonant pressure sensor based on piezoelectric properties of ferroelectric thick films", Sensors and Actuators A, Vol. 31, Pages 153-158, (1992)							
	Prudenziati et al., "Piezoelectric Thick-film Materials and Sensors", Microelectronics International, No. 38, Pages 5-11, (September 1995)							
	Fernandez et al., Processing and microstructure of porous and dense PZT thick films on Al ₂ O ₃ ", Journal of Materials Science, Vol. 30, Pages 5399-5404, (1995)							
	Chen et al., "Dielectric, ferroelectric, and piezoelectric properties of lead zirconate titanate thick films on silicone substrate," Journal Applied Physics, Vol. 77, No. 7, Pages 3349-3353, (April 1, 1995)							
	Cicco et al., "Elastic Surface Wave Devices Based on Piezoelectric Thick-Films", IEEE Transactions on Ultrasonics, Ferroelectrics, and Frequency Control, Vol. 43, No. 1, Pages 73-77, (January 1, 1996)							
	Maas et al., "Thick-film printing of PZT onto silicon", Materials Letter, Vol. 31, Pages 109-112, (1997)							
	Ferrari et al., "Thick-film resonant piezo-layers as new gravimetric sensors", Meas. Science Technology, Vol. 8, Pages 42-48, (1997)							
	Yao et al., "Improved preparation procedure and properties for multiplayer piezoelectric thick-film actuator", Sensors and Actuators, Vol. A71, Pages 139-143, (1998)							
	Akiyama et al., "Development of Lead Zirconate Titanate Family Thick Films on Various Substrates", Jpn. J. Appl. Phys., Vol. 38, Pages 5524-5527, (1999)							
	Beeby et al., "Thick film PZT/micromachined silicon accelerometer", Electronics Letters, Vol. 35, No. 23, Pages 2060-2062, (November 11, 1999)							
/BT/	Ferrari et al., "Multisensor array of mass microbalances for chemical detection based on resonant piezo-layers of screen-printed PZT", Sensors and Actuators, Vol. B68, Pages 81-87, (2000)							
EXAMINER /Brian Talbot/				DATE CONSIDERED 04/25/2007				
EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.								

Form PTO-1449

ATTY. DOCKET NO.
4249-0112PAPPLICATION NO.
10/680,229

**INFORMATION DISCLOSURE CITATION
IN AN APPLICATION**

(Use several sheets if necessary)

APPLICANT
Kui YAO et al.FILING DATE
October 8, 2003GROUP
Unassigned**U.S. PATENT DOCUMENTS**

EXAMINER INITIAL	DOCUMENT NUMBER	Kind	DATE	NAME	CLASS	SUB CLASS	FILING DATE IF APPROPRIATE
	US						
	US						
	US						
	US						
	US						
	US						
	US						
	US						
	US						
	US						

FOREIGN PATENT DOCUMENTS

	Office	DOCUMENT NUMBER	Kind	DATE	COUNTRY	CLASS	SUB CLASS	TRANSLATION	
								YES	NO

OTHER DOCUMENTS

(Include Name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.) date, page(s), volume-issue number(s), publisher, city and/or country where published.

/BT/	Glynne-Jones et al., "An investigation into the effect of modified firing profiles on the piezoelectric properties of thick-film PZT layers on silicon", Meas. Science Technology, Vol. 11, Pages 526-531, (2000)
/BT/	Beeby et al., "Silicon micromechanical resonator with thick-film printed vibration excitation and detection mechanisms", Sensors and Actuators, Vol. A88, Pages 189-197, (2001)
/BT/	Thiele et al., "Processing and Properties of Screen-Printed Lead Zirconate Titanate Piezoelectric Thick Films on Electroded Silicon", J. Am. Ceram. Soc., Vol. 84, No. 12, Pages 2863-2868, (2001)

EXAMINER
/Brian Talbot/DATE CONSIDERED
04/25/2007

EXAMINER: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.



PTO/SB/08a/b (07-05)

Approved for use through 07/31/2006. OMB 0851-0031

U.S. Patent and Trademark Office; U.S. DEPARTMENT OF COMMERCE

Under the Paperwork Reduction Act of 1995, no persons are required to respond to a collection of information unless it contains a valid OMB control number.

Substitute for form 1449A/B/PTO. INFORMATION DISCLOSURE STATEMENT BY APPLICANT (Use as many sheets as necessary)				Complete If Known	
				Application Number	10/680,229-Conf. #5826
				Filing Date	October 8, 2003
				First Named Inventor	Kui YAO
				Art Unit	1762
				Examiner Name	B. K. Talbot
Sheet	1	of	1	Attorney Docket Number	4249-0112P

U.S. PATENT DOCUMENTS					
Examiner Initials*	Cite No. ¹	Document Number	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear
		Number-Kind Code ² (if known)			
/BT/	AA*	US-2002/0171182-A1	11-21-2002	Kim et al.	

FOREIGN PATENT DOCUMENTS						
Examiner Initials*	Cite No. ¹	Foreign Patent Document	Publication Date MM-DD-YYYY	Name of Patentee or Applicant of Cited Document	Pages, Columns, Lines, Where Relevant Passages or Relevant Figures Appear	T ⁶
		Country Code ³ -Number ⁴ -Kind Code ⁵ (if known)				

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant. * CITE NO.: Those application(s) which are marked with an single asterisk (*) next to the Cite No. are not supplied (under 37 CFR 1.98(e)(2)(ii)) because that application was filed after June 30, 2003 or is available in the IFW. ¹ Applicant's unique citation designation number (optional). ² See Kinds Codes of USPTO Patent Documents at www.uspto.gov or MPEP 901.04. ³ Enter Office that issued the document, by the two-letter code (WIPO Standard ST.3). ⁴ For Japanese patent documents, the indication of the year of the reign of the Emperor must precede the serial number of the patent document. ⁵ Kind of document by the appropriate symbols as indicated on the document under WIPO Standard ST.16 if possible. ⁶ Applicant is to place a check mark here if English language Translation is attached.

NON PATENT LITERATURE DOCUMENTS			
Examiner Initials	Cite No. ¹	Include name of the author (in CAPITAL LETTERS), title of the article (when appropriate), title of the item (book, magazine, journal, serial, symposium, catalog, etc.), date, page(s), volume-issue number(s), publisher, city and/or country where published.	T ²

*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609. Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

¹ Applicant's unique citation designation number (optional). ² Applicant is to place a check mark here if English language Translation is attached.

Examiner Signature	/Brian Talbot/	Date Considered	04/25/2007
-----------------------	----------------	--------------------	------------

Birch, Stewart, Kolasch & Birch, LLP

JMS/ta